

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of: Fumitsugu FUKUYO et al.	)	Confirmation No.: 4531
Application No.: 10/537,509	)	Group Art Unit: 2892
Filed: November 30, 2005	)	Examiner: Elias Ullah
For: METHOD FOR CUTTING	)	
SEMICONDUCTOR SUBSTRATE	)	

Commissioner for Patents  
U.S. Patent and Trademark Office  
**Customer Window, Mail Stop Amendment**  
Alexandria, VA 22314

Sir:

**AMENDMENT**

In response to the Office Action dated August 19, 2008, the period for response to which runs through February 19, 2009 by the concurrently-filed petition for a three-month extension of time and corresponding fee payment, please amend the above-identified application as follows.